

Notice of References Cited		Application/Control No. 10/726,744	Applicant(s)/Patent Under Reexamination OLSEN ET AL.	
		Examiner Jeffrey T. Barton	Art Unit 1795	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
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FOREIGN PATENT DOCUMENTS

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	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	H. Bottner, "Thermoelectric Micro Devices: Current State, Recent Developments and Future Aspects for Technological Progress and Applications" Proc. 21st Int. Conf. Thermoelectronics. Long Beach, CA, 25-29 August 2002. pp 511-518.
	V	Sun, C.W. et al, "Crystallization behavior of non-stoichiometric Ge-Bi-Te ternary phase change materials for PRAM application", J. Phys. Condens. Matter. 19 (2007) 446004. 9pp
	W	Kim, D.-H. et al, "Effect of deposition temperaute on the structural and thermoelectric properties of bismuth telluride thin films grown by co-sputtering", Thin Solid Films. 510 (2006) 148-153.
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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